

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Li et al.

Attorney Docket No.: LAM1P098

Application No.: 09/222,588

Examiner: P. Hassanzadeh

Filed: December, 28, 1998

Group: 1763

Title: PERFORTAED PLASMA CONFINEMENT
RING IN PLASMA REACTORS

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the
United States Postal Service as First Class Mail by an Assistant
Commissioner for Patents, Washington, DC 20231 on July 27, 2000.

Signed: _____

**Official
FAX RECEIVED
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GROUP 1700****AMENDMENT**Assistant Commissioner for Patents
Washington, D.C. 20231*Amdt C
#12*

Dear Sir:

In response to the office action dated May 4, 2000, please enter the following
amendments and remarks.

In the ClaimsPlease **AMEND** claims 1, 24, and 35 as follows:

- C/ 1. A plasma processing reactor for processing a substrate comprising:
- a chamber;
 - a top electrode configured to be coupled to a first RF power source having a first RF frequency;
 - a bottom electrode configured to be coupled to a second RF power source having a second RF frequency that is lower than said first RF frequency;

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